



SHEET 1 OF 1

Substitute for forms 1449A/PTO & 1449B/PTO

**FIRST INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

ATTORNEY'S DKT No. 007413-056	APPLICATION No. 10/614,825
APPLICANT Oliver KIENZLE et al.	
FILING DATE July 9, 2003	GROUP Unassigned

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Examiner Initials	Document Number	Kind Code (if known)	Name of Patentee or Applicant of Cited Document	Issue/Publication Date (MM-DD-YYYY)
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NON PATENT LITERATURE DOCUMENTS

Examiner Initials	Include name of author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.		
KR	Hansheng GUO et al., "Charging Phenomena and Charge Compensation in AES on Metal Oxides and Silica," SURFACE AND INTERFACE ANALYSIS, Vol. 25, pp. 390-396 (1997), John Wiley & Sons, Ltd.		
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Examiner Signature	ZIA R. HASHMI	Date Considered	12/27/04
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